



Agent Docket No.: Stanford MxL 01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of)
)
Charles D. SCHAPER)
)
Application No: 09 / 898,521)
)
Filed : July 3, 2001)
)
Title: **Molecular Transfer lithography**)
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Palo Alto, California 94306
June 6, 2002

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR § 1.97

Assistant Commissioner for Patents
U.S. Patent and Trademark Office
Washington, DC 20231

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In accordance with the duty of disclosure under 37 CFR § 1.56 and in accordance with 37 CFR § 1.97 and 37 CFR § 1.98, enclosed is an Information Disclosure Statement PTO-1449B substitute, together with photocopies of the ten articles cited on that form.

It is requested that the cited documents be considered by the Examiner in the examination of the above cited patent application, and that the enclosed copy of the Information Disclosure Statement Form PTO-1449 be initialed by the Examiner to indicate such consideration, and that a copy of this initialed form be returned to the applicants.

Pursuant to 37 CFR § 1.97, the submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made, and is not to be construed as an admission that the information cited within is material to patentability.

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Please address all further correspondence to

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Respectfully submitted,



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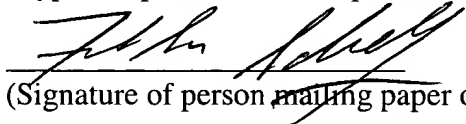
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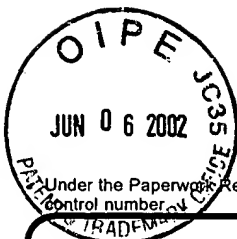
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Substitute for form 1449B/PTO		Complete if Known			
		Application Number	09 / 898,521		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Filing Date	July 3, 2001		
		First Named Inventor	Charles D. SCHAPER		
		Group Art Unit			
		Examiner Name			
Sheet	1	of	1	Attorney Docket Number	STAN MXL 001

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ¹	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		Stephen CHOU, Peter KRAUSS, & Preston RENSTROM. "Imprint Lithography with 25-Nanometer Resolution", Science Vol. 272, April 5, 1996 pp. 85-87, USA.	
		Stephen CHOU, Peter KRAUSS, & Preston RENSTROM. "Nanoimprint Lithography", Journal of Vacuum Science & Technology B Vol. 14(6), Nov/Dec. 1996 pp. 4129-4133, USA.	
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		M. COLBURN, S. JOHNSON, M. STEWART, S. DAMLE, T. TAILEY, B. CHOI, M. WEDLAKE, T. MICHAELSON, S.V. SREENIVASAN, J. EKERDT, & C. Grant WILLSON, "Step and flash imprint lithography: A new approach to high-resolution printing", in Emerging Lithographic Technologies III, Y. Vladimirovsky, ed. Proceedings of the SPIE Vol. 3676, March 1999 pp. 279-389, USA.	
		P. RUCHHOEFT, M. COLBURN, B. CHOI, H. NOUNU, S. JOHNSON, T. BAILEY, S. DAMLE, M. STEWART, J. EKERDT, S.V. SREENIVASAN, J.C. WOLFE, & C. Grant WILLSON, "Patterning curved surfaces: Template generation by ion beam proximity lithography and relief transfer by step and flash imprint lithography", Journal of Vacuum Science & Technology B Vol. 17(6), Nov/Dec. 1996 pp. 2965-2969, USA.	

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

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